

			Aay 22, 2025) rum Breakfasts		
rol, and Automation					7:00 AM
					/:00 AM
	178: Digital Transformation of Industrial Deposition Processes Nager Genety (2017) Transactation (2017) Parasactation (2017) Deposition of American (2017)				
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	Casteward Constitute Hardware				
	Fash Page (PP Pana), LCJ / Me March (Pseuhore GT) Christian (Pseuhore GT) THE: Costings for Thin Ham Photovoltaics				
	11% Cuting for their file Photometric Valer Singer (Incolute of Carl Carl Carl Carl Carl Carl Carl Carl				-
	THE: CVD and ALD Processing Matt Writers (Fourtheast) database Satone)				
	TTR: This (Film Service) (Film Servi				
		TFB: Ultra-thin Flexible 0 Chris Stoessel (StoesselConsulting	Slass - the next big thing?) / J3rg Neithardt (Fraucholes-FEP) sont B		
ve Atomic Scale Processes					
Tenessue D/E	Tenessee A	Tamessee B	Tenussee C	Tenessee D/E	
(Program track daily room assignment)	(Program track daily room assignment)	(Program track daily room assignment) 10 minute p	(Program track daily room assignment) passing break	(Program track daily room assignment)	8:30 AM 8:40 AM
	Kaynola Angel Yangsach Angenen National Laboratory Markina Laborator for Januar Davadition architecturing Charling and Paralities Solution of Thin Rim (much Processos				8:50 AM 9:00 AM 9:10 AM
	Machine Lawring for Atomic Layer Deposition: Accelerating Optimization and Predicting Scale Up of Thin Film Growth Processes (Temassee C) 20 minutes passing brank				9:20 AM 9:30 AM
Exhibitor Innovator Showcase (EIS) Iscum Process Monitoring, Control and Automation Using Remote Plasma Optical Emission Spectroscopy (Joe Birddey - Gencoa Ud)		HIPINS (HP) Enhancing Uniformity and Stability through OSI-Based Feedback Control in an Induratin Raid-to-dail WithRei Conter (a-clang He - Feng Chia University)		Coatings and Processes for Biomedical Applications (8T) Spattered Coatings on Paper – First Results of a Frankbilty Study (Christina Lehmann – Technical Iniversity Erzunschweig)	2:40 AM
Optical Emission Spectroscopy (Joe Brindley - Gencos Ltd) Exhibitor Innovator Showcase (EIS)	Large Area (LAinv) Trends is Large Area Glass Costing (Paul Morgensen - Saint Gobain Glass France)	Industrial Roll-to-Roll WPMS Caster (Jo-Liang He - Feng Chia Liniventry) HIPIMS (HP)	Plasma Processing and Diagnostics (PPinv) Plasma Nitiding and PACVD Coating as Complementary Technology for PVD for Big Industrial Applications (Stefan Haas - Robig GmbH & Co KG)	(Christina Lehmann - Technical Iniversity Ensurschweig) Coatings and Processes for Biomedical Applications (81) Identification of New Alays for Biomedical Applications using Combinatorial	9:50 AM
DOMINO- Efficient Solutions For Thin Film Equipment (Reto Roschi - Gerlikon Balsen)		HIPIMS (HP) Novel Reactive Process Control in Industrial HPIMS (Rafael Sanchez Reategui - Ionautics)		Approaches (Jetfrey Hettinger - Rowan University)	10:00 AM
Exhibitor Innovator Showcase (EIS) EUCON Zeoleon 1 IM/201: Precision Control for Maximum Repeatability and	Large Area (LA) In-Line Coating System With Hollow Cathodo Inverted Cylindrical Magnetron For		Plasma Processing and Diagnostics (PP) Simulating the impact of Loading Density on to Coasing Uniformity in Batch Coaters	Coatings and Processes for Biomedical Applications (BT) Use of Elevated Temperature X-Ray Diffraction for Investigating Biomedical	10:10 AM
Unmatched Crystal Efficiency (Sheidon Wayman - INFICON)	This Film Applications On Long Tubes And Continuous Fibers (Ivan Shchelkanov - Starfire Industries LLC)	HIPINS (HP) bifusnice of Pulse Dustrian an Filinan Chemistry and Thir Film Strandthof Plasmotic Titanian Nitride Deputited by Canada Cannon Englished HVMIII. HVMIIDENT PLASMOTED DUSKT PRESENTATION (DBas Multi-Shelfeld Patient One-weig) HIPINS (HP)	(Krystof Mroaek - PlasmaSolve s.r.o.)	Coatings (Theodore Scabarool - Rowan University) Coatings and Processes for Biomedical Applications (BT)	10:30 AM
	Large Area (LA) Ion Source Pretreatment of Large Area Glass Substrates (Marcus Frank - Bühler Abenau GmbH)	HIPING TIB2 Coating onto Silter Cutters to Enhance Auminum Capacitor Fol Cutting Quality (Jul-Chang Tiul - Fong Chia University)	Plasma Processing and Diagnostics (PP) Hollow Carbade Processes (Ralf Bandoof - Fraueholer IST)	Electrochemical and Microstructural Evolution of Neural Stimulation Electroder Coated with Antibacterial Metal Oxide Thin Films (Bitl Panchal - Desail University)	10:40 AM
Exhibitor Innovator Showcase (EIS) Peortia Manadam Southering Earthack Control 'Earthalthe for Surgers'	Large Area (LA) Impact of AC Waveform on Plasma Dynamics and Film Growth – Sine Wave vs	HIPINS (HP) Experiments and Modelling of High Power impulse Magnetron Sputtering	Plasma Processing and Diagnostics (PP) Fast Kinetic Modeling of the Plasma Evolution, Etch Rate and Deposition Profile in Detect Curver Magnetons Spattering (Daniel Main - Tech-X Cosponsion)		10:50 AM
Reactive Magnetron Sputtering Feedback Control, 'Flexibility for Success' (Dermot Monaghan - Gencoa Ltd) Exhibitor Improvatory Shrvaraso (FES)	Square Wave (Adam Obrusnik - PlasmaSolve s.r.o.)	Discharges with Metallic Target (Jon Tomas Gudmundisson - University of Iceland)	Direct Current Magnetion Sputtering (Daniel Main - Tech-X Corporation)	Coatings and Processes for Biomedical Applications (BTinv) Herschical Surface Reductoring: The Technology of the Fature for Sustainable High Performing and Multifunctional Neural Interfacing Electrodes and Might Performing and Multifunctional Neural Interfacing Electrodes and	* 11:10 AM
Exhibitor Innovator Showcase (EIS) Unlocking Innovation: Solving Complex Challenges Through Collaborative Engineering (Jimmy Haight - Semicore Equipment, Inc.)	Large Area (LA) High Rate - High Quality Thin Films Made Possible with a Game Changing Plasma Source (David Stevenson - Angest, Inc.)	HIPIMS (HP) Black Metal Film Prepared by Gas Flow Sputtering for Capacitor Electrode Purpose (Ping-Yen Hsieh - Feng Chia University)	Plasma Processing and Disconstine (PDiny).	Microelectrode Arrays (Shahram Armini - Pulae Technologies Inc.)	11-20 AM
Exhibitor Innovator Showcase (EIS)			Plasma Processing and Diagnostics (PPinv) Data-Integrated Modeling for Memistive Davice Processing (Jan Trieschmann - Kiel University)		11:30 AM
Physical Vapor Deposition (PVD) Combined Processes (Carlos Guerra - Swiss Cluster)	Large Area (LA) Large-Area Coating Innovations by HCVAC for Energy Applications (Zhiming Luo - Guangdong Huicheng Vacuum Technology Co., Ltd)	HEPEMS (HPFess) Reactive Sputtering of High Entropy Allow Windsh, Cashida, and Oxide Thin Films by HEPEMS: Effect of Reactive Gas Films Rates jsts-Wei Lee-Ming Chi University of Technology)			11:50 AM
Exhibitor Innovator Showcase (EIS) Plasma Engineering LLC: Consulting and Education in Plasmas and Plasma Applications	Large Area (LA) Bringing Novel Applications to Large Area with Advanced Sputtering Solutions (Kenny Vernieuwe - Soleras Advanced Coatings)	by HPMMS: Effect of Reactive Gas Flow Rates Jyh-Wei Lee - Ming Chi University of Technology)	Plasma Processing and Diagnostics (PP) An Understanding of the QMS and Relevance to the ITER-ORGA Mission (Chris Marcus - U.T Battele for GRAL)		12:00 PM
Applications (André Anders - Plasma Engineering LLC) Exhibitor Innovator Showcase (EIS)	Contrary Contrary Contrary Advanced Costingia		permanente e v. r Mattelle for GROKL		12:10 PM
Benefits of Telemark's Low Pressure ion Sources (Wayne Sainty - Telemark)		Lunch break			12:20 PM
Exhibitor Innovator Showcase (EIS) Introducing an Internal Meximit Flat Induction Coupled Plasma Source for Chamber and Substrate Proceeding (Steve Simons - Manitou Systems Inc.)			Atomic I page Atomic fait		12:40 PM
(Steve Simons - Manitou Systems Inc.)	Large Area (LA) The Advantages of Bidirectional Publing Technique for Magnetron Sputtering (Yilei Shen - TRUMPF Höttinger GmbH + Co. KG)		Atomic Layer Processing (AL) Thermal Atomic Layer Deportion of Low Residvicity Metallic Films for High Aspect- Ratio Via Seried (Dane Lindblad - Forge Nano)		12:50 PM
			(Dane Lindblad - Forge Nano)		1:00 PM
	Large Area (LA) Simulation of Rotary Magnetion Discharges Excited by Different Frequencies (Ken Nauman - Sputterleg Components Inc.)		Atomic Layer Processing (ALinv) Spatial Atomic Layer Deposition: A New Revolution in Ultra-Fast Production of		1:10 PM 1:20 PM
		HIPIMS Panel Discussion and Workshop	Conformal and High-Quality Thin-Film Coatings (Philipp Maydannik - Benneq)		1:30 PM
		(2 hrs)	Atomic Layer Processing (AL)		1:40 PM
		"Success Stories and Positive Adoption of HIPIMS"	Atomic Layer Processing (AL) Challenges and Advances in ALD for High Aspect Ratio Structures - SPONSORID STUDENT PRESENTATION (Josh Pinder - Brigham Young University)		1:50 PM 2:00 PM
					2:10 PM
					2:20 PM
					2:30 PM 2:40 PM
		HIPIMS (HP) Robust Plasmonically-Active Nanoscale Multilayer TINNbN Coatings (Aratiun P. Ehiasarian - Sheffald Hallam University)			2:50 PM
					3:00 PM
		HIPIMS (HP) Impact of the Pulse Length in HIPIMS on the Departison Rute, Ion Metal Rux Fraction and Ageo Ion Rux - SPOKGOBC DSTUDINT PASSINTATION (Martin Ondry&I - Masaryk University)			3:10 PM
		20 minute refreshment break			3:20 PM
			1		3:40 PM
		HIPIMS (HP) Optimizing HIPIMS Processes in Real-Time by Pulse-Resolved Spectroscopic and Electrical Plasma Process Control (Jae-Peter Urbach - PLASUS GmbH)			3:50 PM
		HIPIMS (HP)			4:00 PM 4:10 PM
		HEPIMS Deposited Constantan Alloy Film for Stretchable Thin-Film Strain Gauge (Yu-Wen Chen - Feng Chia University)			4:20 PM
		HEDRAG FAMILIAN			4:30 PM
		HIPIMS (HPinv) HIPIMS Technology in industrial Applications (Konrad Fadenberger - Gerlikon Surface Solutions)			4:40 PM
					4:50 PM 5:00 PM
		HIPIMS (HP) HIPIMS-TIQ2 As Electron Transport Layer for Flexible Perovskite Solar Cells Application			5:10 PM
		Application (Pel-En Fang - Feng Chia Liniversity) HIIPIMIS (HP)			5:20 PM
		HIPINS (HP) Plasma-Crafted Colours: Hybrid HIPINS Costings with Engineered Aesthetics and Achesion (Anas Ghallane - Availuae Costing Technologies)			5:30 PM
		HIPIMS (HP) Explaining the HIPIMS Process from an Application Perspective (Daniel Loch - Trampf Hättinger GmbH & Co. KD)			5:50 PM
		(Duniel Loch - Trumpf Hättinger GmbH & Co. KG)			6:00 PM
		Young Mentors 6:00-7	s/Farewell Party 1:30 PM		
		(Wate	rs Edge)		
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					8:00 P
					10:00 P
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